

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Shimomura, et al.
Int'l Appl. No.	:	PCT/JP2004/015480
Int'l Filing Date	:	October 20, 2004
For	:	POLISHING PAD AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD
Examiner	:	Unknown
Group Art Unit	:	Unknown

PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Prior to calculation of the number of claims, please amend the present application.

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper.

**Remarks/Arguments** begin on page 6 of this paper.